

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Patent Application of	)	
	)	
Shuzo SATO et al.	)	ATT: APPLICATION BRANCH
	)	
Serial No. To be assigned	)	
	)	
Filed: March 8, 2001	)	
	)	
For: METHODS OF PRODUCING AND	)	
POLISHING SEMICONDUCTOR DEVICE	)	
AND POLISHING APPARATUS	)	

PRELIMINARY AMENDMENT ACCOMPANYING FILING

Commissioner for Patents  
Washington, D.C. 20231

Sir:

Prior to the initial examination, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 32, line 3, change "Fig. 22" to -- Fig 22A and Fig 22B--

REMARKS

This Preliminary Amendment is requested to accurately identify the drawings. No new matter has been added. Entry of this amendment is requested.

Respectfully submitted,

Date: March 8, 2001



~~Pat~~ Ronald P. Kananen  
Registration No. 24,104

**RADER, FISHMAN & GRAUER, PLLC**

Lion Building  
1233 20<sup>th</sup> Street, N.W.  
Washington, D.C. 20036  
Tel: (202) 955-37650